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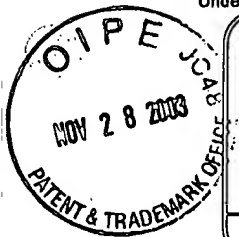


PTO/SB/08B (10-96)

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Substitute for form 1449B/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 2 of 2

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| Application Number | 09/649,569 |
| Filing Date | AUGUST 28, 2000 |
| First Named Inventor | PATEL et al. |
| Group Art Unit | 1746 |
| Examiner Name | Unknown |
| Attorney Docket Number | P06-US |

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS

| Examiner Initials ¹ | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------------------|-----------------------|---|----------------|
| | EA | STRELLER et al., "Selectivity in Dry Etching of Si(100) and XeF ₂ and VUV Light", Elsevier Science B.V., Applied Surface Science, (1996), 106: pp. 341-346 | |
| | EB | VUGTS et al., "Si/XeF ₂ Etching: Temperature Dependence", J. Vac. Sci. Technol. A 14(5), (Sep/Oct 1996), pp. 2766-2774 | |
| | EC | WANG et al., "Gas-Phase Silicon Etching with Bromine Trifluoride", Transducers '97, 1997 International Conference on Solid-State Sensors and Actuators, Chicago (June 16-19), pp. 1505-1508 | |
| | ED | WINTERS, H.F., "Etch Products from the Reaction of XeF ₂ with SiO ₂ , SiO ₃ , Si ₃ N ₄ , SiC, and Si in the Presence of Ion Bombardment", J. Vac. Science Technology B 1(4), (Oct-Dec 1983), pp. 927-931 | |
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| | EF | GILDEMEISTER, J.M., "Xenon Difluoride Etching System", (Nov 17, 1997) | |
| | EG | "Xenon Difluoride Isotropic Etch System", Seeing is Believing, Surface Technology Systems Ltd. brochure, Newport, UK (date unknown) | |
| | EH | Assorted promotional literature, Surface Technology Systems Ltd., Newport, UK (July 28, 1999) | |
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Date
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AUGUST 28, 2000

PATEL et al.

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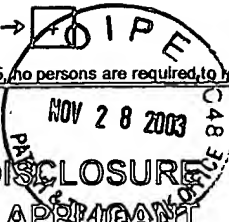
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| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary) | | | Application Number | 09/649,569 |
| | | | Filing Date | AUGUST 28, 2000 |
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| | | | Examiner Name | Unknown |
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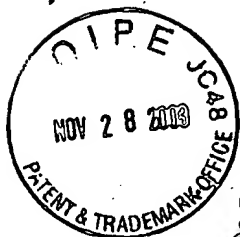
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| | | Application Number | 09/649,569 |
| | | Filing Date | AUGUST 28, 2000 |
| | | First Named Inventor | PATEL et al. |
| | | Art Unit | 1746 |
| | | Examiner Name | PURNELL, A. |
| | | Attorney Docket Number | P06-US |
| Sheet | 1 | of | 3 |

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| Examiner Initials ¹ | Cite No. ¹ | Document Number | | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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| Examiner Initials ¹ | Cite No. ¹ | Foreign Patent Document | | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear | T ⁶ |
| | | Country Code ³ | -Number ⁴ - Kind Code ⁵ (if known) | | | | |
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| | GJ | JP-1986/61181131-A | | 08-13-1986 | Shinji et al. | | |

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